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ABSTRACT OF THE DISCLOSURE

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In a projection aligner for illuminating a pattern on a mask with a luminous flux from a light source through an illumination system and projecting the pattern onto a wafer with a projection optical system, a titanium oxide ( $\text{TiO}_2$ ) film is provided on the surface of at least one unit constituting the projection aligner. Thus, contamination of the projection aligner can be prevented.

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